

ACKNOWLEDGEMENT RECEIPT

Electronic Version 1.1

Stylesheet Version v1.1.1

Title of Invention

HIGH PRESSURE PROCESSING CHAMBER FOR SEMICONDUCTOR SUBSTRATE

Submission Type : Information Disclosure
Statement

Application Number:

09/912844



EFS ID:

81783

Server Response:

Confirmation Code	Message
ISVR1	Submission was successfully submitted - Even if Informational or Warning Messages appear below, please do not resubmit this application
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First Named Applicant:

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Attorney Docket Number:

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File Listing:

Doc. Name	File Name	Size (Bytes)	Date Produced (yyyymmdd)
us-ids	SSI_00501-usidst.xml	1547	2005-04-07
us-ids	us-ids.dtd	7763	2005-04-07
us-ids	us-ids.xsl	12026	2005-04-07
package-data	SSI_00501-pkda.xml	1713	2005-04-07
package-data	package-data.dtd	27025	2005-04-07
package-data	us-package-data.xsl	19263	2005-04-07
Total files size		69337	

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